

Electrodynamics of Plasma Oscillations in Semiconductor Microdevices with Two-Dimensional Electron Channels

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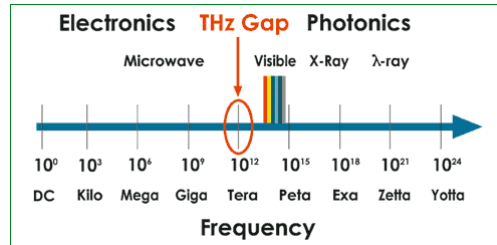
W. KNAP

GES CNRS-Universite Montpellier2 UMR 5650, 34900 Montpellier, France

Outline of the Talk

1. Can plasmonic devices fill a THz gap?
2. Remarks on the fundamentals of two-dimensional plasmons. Plasmon modes in a HEMT structure. When the electromagnetic effects are important?
3. Slot diode with two-dimensional electron channel (unscreened plasmons): electromagnetic description
4. Screened plasma oscillations (electromagnetic description). Interaction of gated (screened) and ungated (unscreened) plasmons in a HEMT structure
5. Conclusions

Applications of THz Technology



- Imaging:
 - THz tomography
 - Explosive and mine detection
 - Security scanners
- Biotechnology: molecular sensors
- Radio astronomy
- Atmospheric measurements
- Fusion Plasma diagnostics
- IC interconnects
- Advanced short-range radars
- Short Range Hidden Communications
- "Last mile internet" solutions

Terahertz Gap

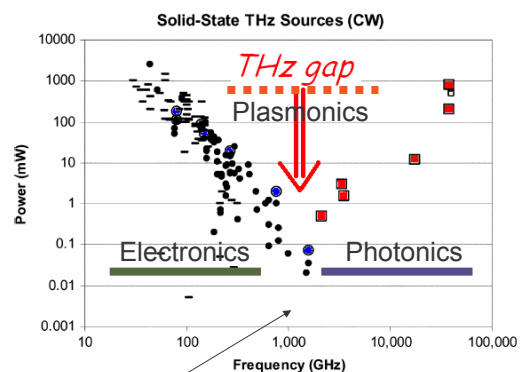
From: T. W. Crowe *et al*, IEEE J. Solid-State Circuits **40**, 2104 (2005)

■ Quantum cascade lasers

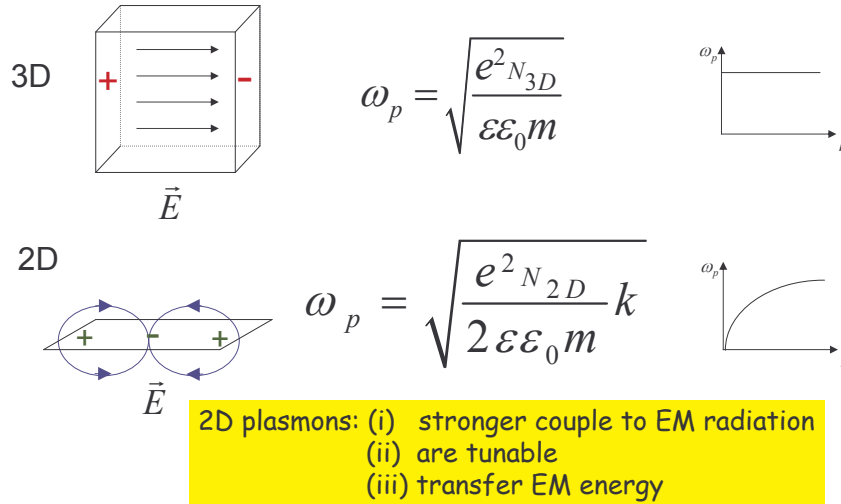
● Frequency multipliers

- Other solid-state electronic sources

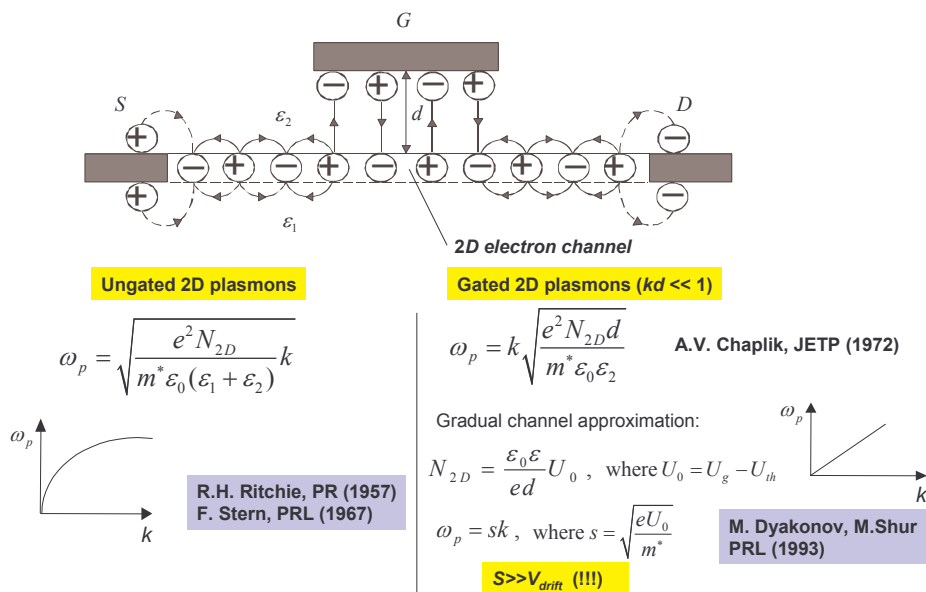
Blue symbols correspond to cryogenic sources



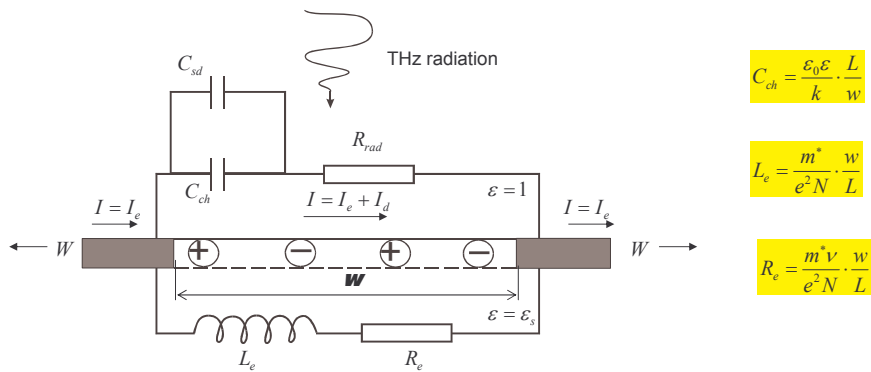
Dispersion of Plasma Waves: 2D vs 3D



Plasmon Modes in a HEMT Structure



Slot Diode with 2DElectron Channel



$$C_{ch} = \frac{\epsilon_0 \epsilon}{k} \cdot \frac{L}{w}$$

$$L_e = \frac{m^*}{e^2 N} \cdot \frac{w}{L}$$

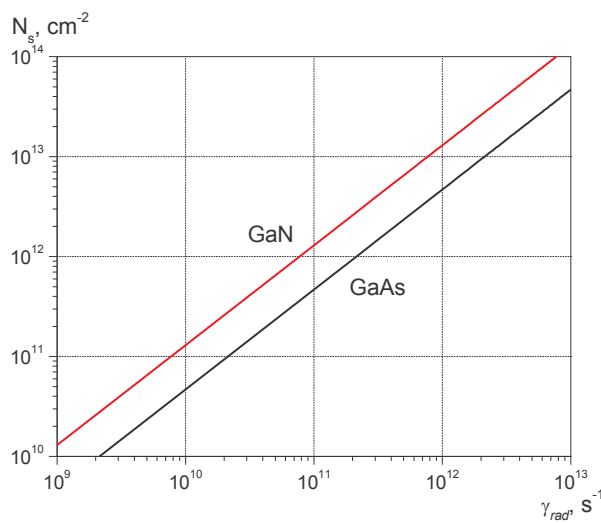
$$R_e = \frac{m^* v}{e^2 N} \cdot \frac{w}{L}$$

Electrostatic description:

$$R_{rad} = 0 \quad \& \quad C_{sd} = 2.83 \times 10^{-3} (\epsilon_s + 1) \ln \left[4 \left(1 + 2 \frac{W}{w} \right) \right] L [\text{fF}] \quad \left(\frac{W}{w} > 0.75 \right)$$

M.S. Shur, GaAs Devices and Circuits, Plenum, N.Y., 1987
P.J. Burke et al, *Appl. Phys. Lett.*, vol. 76, No. 6, pp. 745, 2000
V. Ryzhii et al, *Appl. Phys.*, vol. 93, No. 12, pp.10041, 2003

Radiative Damping of Uniform Oscillating Current in a Homogeneous 2D Electron System



$$\gamma_{rad} = \frac{e^2 N_s}{2m^*} \frac{Z_0}{\sqrt{\epsilon}}$$

V.V. Popov et al.
JETP (1996)

S.A. Mikhailov
Phys. Rev. B (1998)

Electromagnetic Description of Plasmons in FET Structures

- The Maxwell equations are re-written in the Fourier representation
- Using the electrodynamic boundary conditions in the channel and gate planes, the Fourier amplitudes of the oscillating-electron-current density are related to those of the in-plane THz electric field in the gate and electron channel planes
- Equalizing the sheet electron current density obtained in the previous steps to that in the Ohm's law yields the integral equation for the current density in the gate contact
- The integral equation is solved numerically by the Galerkin method through its projection on an orthogonal set of the Legendre polynomials

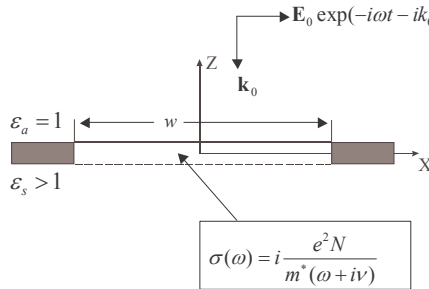
Sheet conductivity of the 2D electron channel

$$\sigma(\omega) = i \frac{e^2 N_{2D}}{m^* (1 - i\omega\tau)}$$

V.V. Popov et al., JETP (1996, 1998, 2002) V.V. Popov et al. JAP (2003, 2005)

Electromagnetic Description of a Slot Diode with 2D Electron Channel

V.V. Popov et al., Semiconductors (2005)



Integral equation for the electric field in the slot:

$$\sigma(\omega) E_x(x) = \int_{-w/2}^{w/2} G(x, x') E_x(x') dx' + \frac{2E_0}{Z_0}$$

$$G(x, x') = \int_{-\infty}^{\infty} dk_x G(k_x) \exp[ik_x (x - x')]$$

$$G(k_x) = \frac{(\chi_a + \chi_s)}{Z_0} \quad \chi_{a(s)} = \varepsilon_{a(s)} \frac{k_0}{k_z}$$

Induced field in the ambient medium:

$$\mathbf{E}_a^{(ind)}(\mathbf{r}) = \mathbf{E}_0 \exp(ik_0 z) + \int_{-\infty}^{\infty} \mathbf{E}_a^{(sc)}(k_x) \exp(i\mathbf{k}_a \mathbf{r}) dk_x$$

Total field in the substrate:

$$\mathbf{E}_a^{(tot)}(\mathbf{r}) = \int_{-\infty}^{\infty} \mathbf{E}_s^{(sc)}(k_x) \exp(i\mathbf{k}_s \mathbf{r}) dk_x$$

$$k_z = \pm \sqrt{k_0^2 \varepsilon_{a(s)} - k_x^2} \quad k_0 = \frac{\omega}{c}$$

$$E_x(x) = \sum_{n=0}^{\infty} a_n P_n(2x/w)$$

Characteristic Electromagnetic Lengths

V.V. Popov et al., Semiconductors (2005)

Scattering Length:

$$L_{a(s)}^{(sc)} = \frac{P_{a(s)}}{P_0}, \quad L^{(sc)} = L_a^{(sc)} + L_s^{(sc)}$$

Absorption Length:

$$L^{(ab)} = \frac{Q}{P_0},$$

$$P_{a(s)} = \frac{\pi}{Z_0} \int_{-k_0\sqrt{\epsilon_{a(s)}}}^{k_0\sqrt{\epsilon_{a(s)}}} \mathbf{n}_{a(s)} \frac{\mathbf{k}_{a(s)}}{k_0} \left| \mathbf{E}_{a(s)}^{(sc)}(k_x) \right|^2 dk_x$$

$$Q = \frac{1}{2} \int_{-w/2}^{w/2} |E_x(x, 0)|^2 \operatorname{Re}[\sigma(\omega)] dx$$

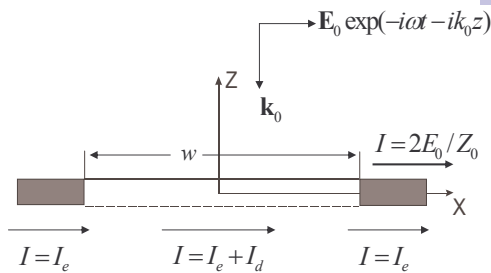
Extinction Length:

$$L^{(ex)} = \frac{4\pi}{|E_0|^2} \operatorname{Re} \left[\mathbf{E}_0^* \mathbf{E}_a^{(sc)}(k_x = 0) \right] - \text{optical theorem}$$

$$W = P_a + P_s + Q \quad \Rightarrow \quad L^{(ex)} = L^{(sc)} + L^{(ab)} - \text{energy conservation}$$

High-Frequency Impedance of the Slot Diode

V.V. Popov et al., Semiconductors (2005)



$$Z = R + iX = \frac{1}{I} \int_{-w/2}^{w/2} E_x(x) dx$$

$$I = \frac{2E_0}{Z_0}$$

Characteristic resistances of the diode:

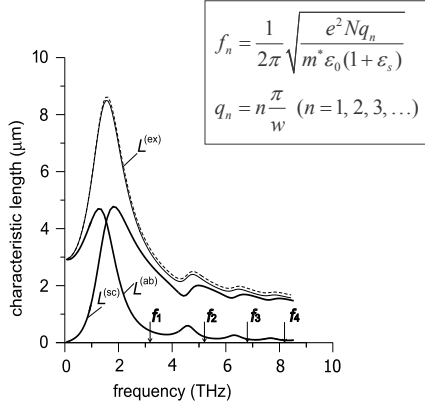
$$R = R_e + R_{rad} = \frac{Z_0 L^{(ex)}}{4}$$

$$R_e = \frac{Z_0 L^{(ab)}}{4}$$

$$R_{rad} = \frac{Z_0 L^{(sc)}}{4}$$

Terahertz Response of the Slot Micro-Diode

Characteristic Lengths:



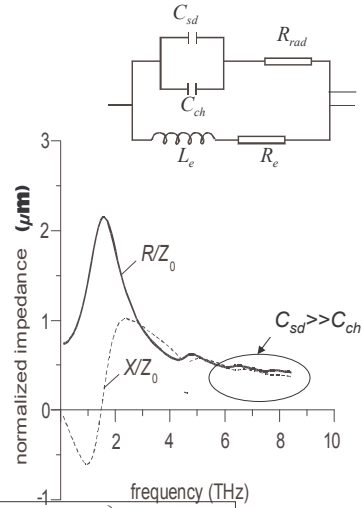
$$\begin{aligned} w &= 1.3 \mu\text{m} \\ N &= 3 \cdot 10^{12} \text{ cm}^{-2} \\ \nu &= 4.35 \cdot 10^{12} \text{ s}^{-1} \\ \epsilon_s &= 13.88 \\ m^* &= 0.042 m_0 \end{aligned}$$

Electrostatic
description:

$$\left. \begin{aligned} R &\rightarrow 0 \\ X &\rightarrow 0 \end{aligned} \right\} \text{at } f \rightarrow \infty$$

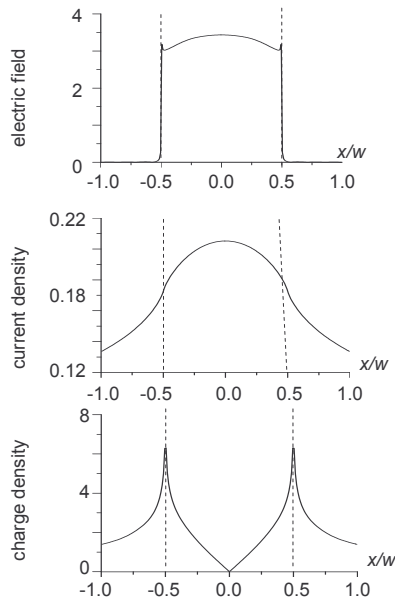
V. Ryzhii et al, *Appl. Phys.*, vol. 93, No. 12, pp.10041, 2003

Diode Impedance:

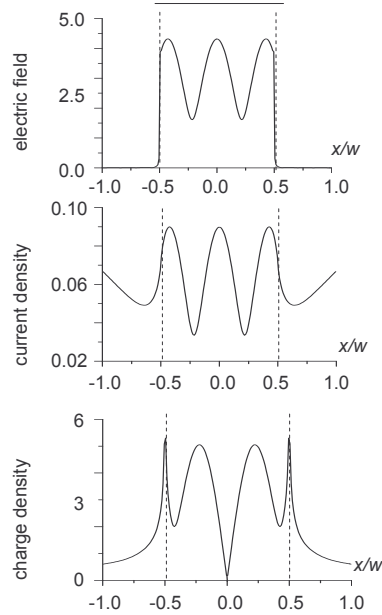


Plasmon Modes of the Slot Diode

Fundamental mode

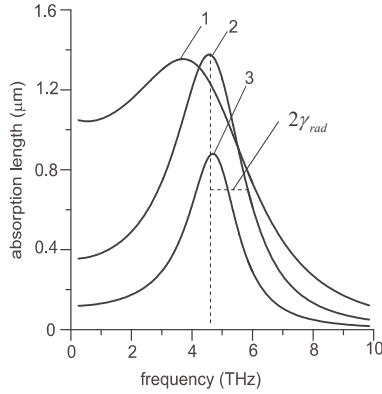


Second mode

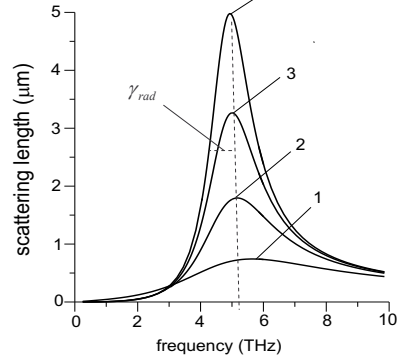


Terahertz Response of the Slot Nano-Diode

В.В. Попов и др., ФТП (2005)



$$\begin{aligned} w &= 0.1 \mu\text{m} \\ N &= 3 \cdot 10^{12} \text{cm}^{-2} \\ \epsilon_s &= 13.88 \\ m^* &= 0.042 m_0 \end{aligned}$$

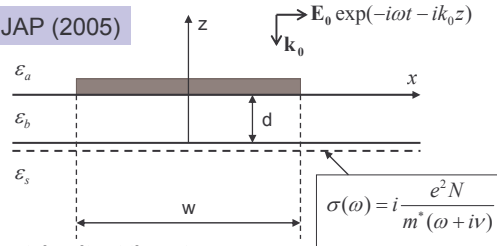


$$\begin{aligned} 1 - & \nu = 2 \cdot 10^{13} \text{ s}^{-1} \\ 2 - & \nu = 7 \cdot 10^{12} \text{ s}^{-1} \\ 3 - & \nu = 2.3 \cdot 10^{12} \text{ s}^{-1} \\ 4 - & \nu = 0 \end{aligned}$$

$$\begin{aligned} A &= A_{\text{max}} \\ @ \quad \gamma_{\text{rad}} &= \nu \\ \downarrow \\ Z_{\text{diode}} &= Z_0 \end{aligned}$$

Electromagnetic Modelling of Gated Plasma Oscillations in 2D Electron Channel

V.V. Popov et al., JAP (2005)



Integral equation for current density at the gate:

$$\begin{aligned} \int_{-l/2}^{l/2} \hat{G}(x, x') I_x(x', d) dx' &= 2\sqrt{\epsilon_a} \frac{\hat{G}_0}{Z_0} E_0, \quad \hat{G}(x, x') = \int_{-\infty}^{+\infty} \hat{G}(k_x) \exp[ik_x(x - x')] dk_x, \quad \hat{G}_0 = \hat{G}(k_x = 0) \\ \hat{G}(k_x) &= \frac{\text{ctg}(k_{z,b} d) + \chi_s / \chi_b}{\chi_b - \chi_a \chi_s / \chi_b - \text{ctg}(k_{z,b} d)(\chi_a + \chi_s)}, \quad \chi_{a(b)} = \epsilon_{a(b)} \frac{k_0}{k_{z,a(b)}}, \quad \chi_s = \epsilon_s \frac{k_0}{k_{z,s}} + Z_0 \sigma(\omega) \end{aligned}$$

Induced electric field in the ambient medium:

$$\mathbf{E}_a^{(\text{ind})}(x, z) = \mathbf{E}_0^{(r)} \exp(ik_0 z) + \int_{-\infty}^{+\infty} \mathbf{E}_a^{(\text{sc})}(k_0) \exp(ik_x x + ik_{z,a} z) dk_x, \quad k_{z,a(s)} = \sqrt{k_0^2 \epsilon_{a(s)} - k_x^2}, \quad k_0 = \omega / c$$

Total electric field in the substrate:

$$\mathbf{E}_s(x, z) = \mathbf{E}_0^{(t)} \exp[-ik_0 \sqrt{\epsilon_s}(z + d)] + \int_{-\infty}^{+\infty} \mathbf{E}_s^{(\text{sc})}(k_x) \exp[ik_x x - ik_{z,s}(z + d)] dk_x$$

Characteristic Electromagnetic Lengths of Partially Gated 2D Electron Channel: Definitions

Scattering Length:

$$L_{a(s)}^{(sc)} = \frac{P_{a(s)}}{P_0}$$

$$L^{(sc)} = L_a^{(sc)} + L_s^{(sc)}$$

Absorption Length:

$$L^{(ab)} = \frac{Q}{P_0}$$

$$Q = 2\pi \operatorname{Re} \left\{ \sigma(\omega) \sqrt{\varepsilon_s} \left[\mathbf{E}_0^{(i)} \right]^* \mathbf{E}_s^{(sc)}(k_x=0) \right\} + \pi \operatorname{Re} \left\{ \sigma(\omega) \right\} \int_{-\infty}^{+\infty} \left| \mathbf{E}_s^{(sc)}(k_x) \right|^2 dk_x$$

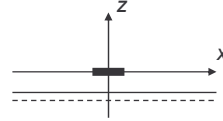
$$P_{a(s)} = \frac{\pi}{Z_0} \int_{-k_0 \sqrt{\varepsilon_a(z)}}^{k_0 \sqrt{\varepsilon_a(z)}} \mathbf{n}_{a(s)} \frac{\mathbf{k}_{a(s)}}{k_0} \left| \mathbf{E}_{a(s)}^{(sc)}(k_x) \right|^2 dk_x$$

Extinction Length:

Energy conservation law $L^{(ex)} = L^{(sc)} + L^{(ab)}$

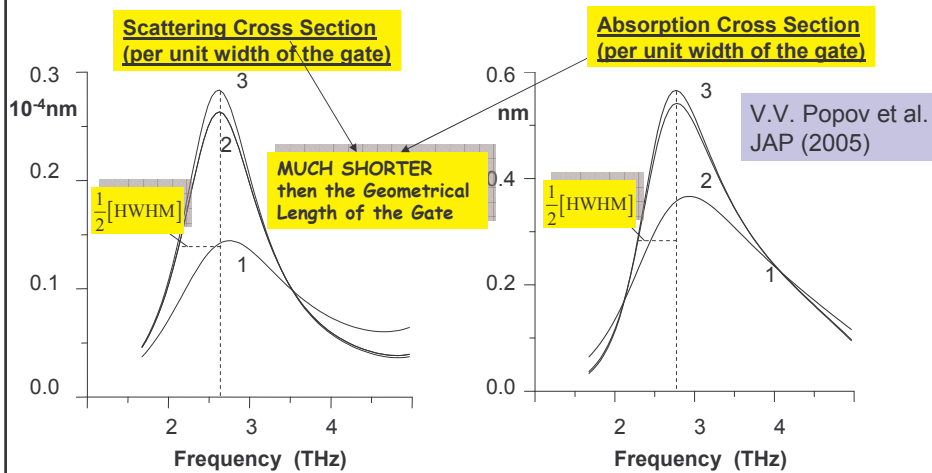
$$L^{(ex)} = \frac{4\pi}{|E_0|^2} \operatorname{Re} \left\{ \sqrt{\varepsilon_a} \left[\mathbf{E}_0^{(i)} \right]^* \mathbf{E}_a^{(sc)}(k_x=0) + \sqrt{\varepsilon_s} \left[\mathbf{E}_0^{(i)} \right]^* \mathbf{E}_s^{(sc)}(k_x=0) \right\}$$

Optical theorem



V.V. Popov et al., JAP (2005)

THz Scattering and Absorption by Gated Plasmons in a Single-Channel HEMT

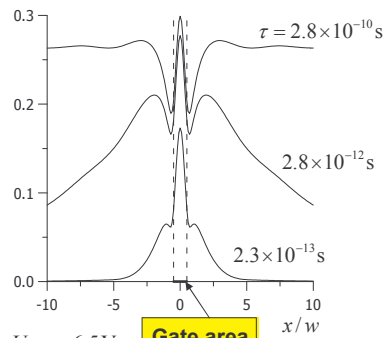


$$U_{th} = -1.17 \text{ V}, \quad U_g = -1 \text{ V} \quad (N_s = 4.386 \times 10^{11} \text{ cm}^{-2}), \quad m^* = 0.042 m_0, \quad w = 60 \text{ nm}, \quad d = 10 \text{ nm}, \quad \varepsilon_s = \varepsilon_b = 13.88$$

$$\tau = 2.3 \times 10^{-13} \text{ s (curve 1); } 2.8 \times 10^{-12} \text{ (curve 2); } 2.8 \times 10^{-10} \text{ (curve 3)} \rightarrow \frac{1}{2\pi\tau} < 10^{-3} \text{ THz}$$

Leakage of Gated Plasmons into Ungated Regions of 2D Channel

In-plane electric field distribution in the channel (arb. units):



$U_{th} = -6.5 \text{ V}$

$U_g = -5.54 \text{ V}$ ($N = 4.386 \times 10^{11} \text{ cm}^{-2}$)

$m^* = 0.042 m_0$

$w = 400 \text{ nm}$

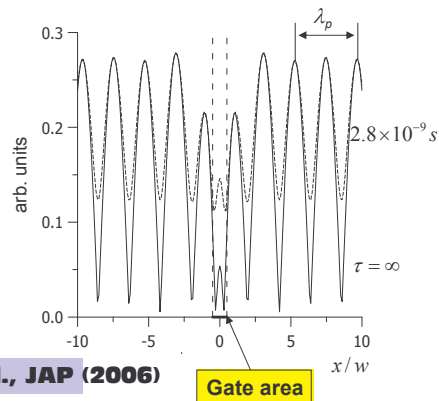
$d = 167 \text{ nm}$

$\epsilon_s = \epsilon_b = 13.88$

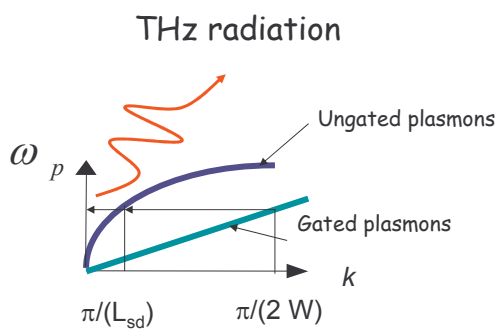
V.V. Popov et al., JAP (2006)

$$\omega^2 = \frac{e^2 N}{2\epsilon\epsilon_0 m^*} k, \quad k = \frac{2\pi}{\lambda_p}$$

$$\bar{\epsilon} = \frac{1}{2} \left[\epsilon_s + \epsilon_b \frac{1 + \epsilon_b \tanh(kd)}{\epsilon_b + \tanh(kd)} \right]$$

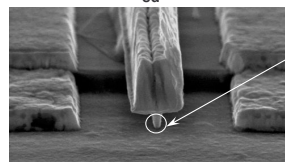
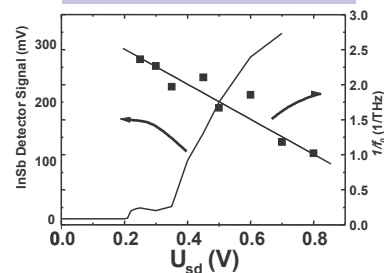


THz Generation in Nanometer-Gate HEMT via Gated-Ungated Plasmon Interaction



The most efficient THz generation occurs when BOTH the ungated and gated plasmons are in resonance

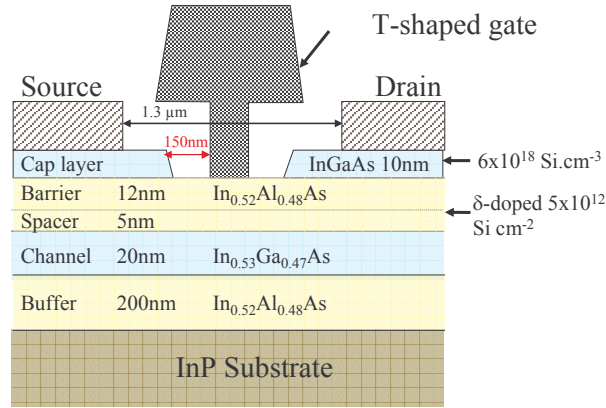
**Knap W. et al, APL (2004)
IEEE Spectrum (May 2004)**



60-nm gate

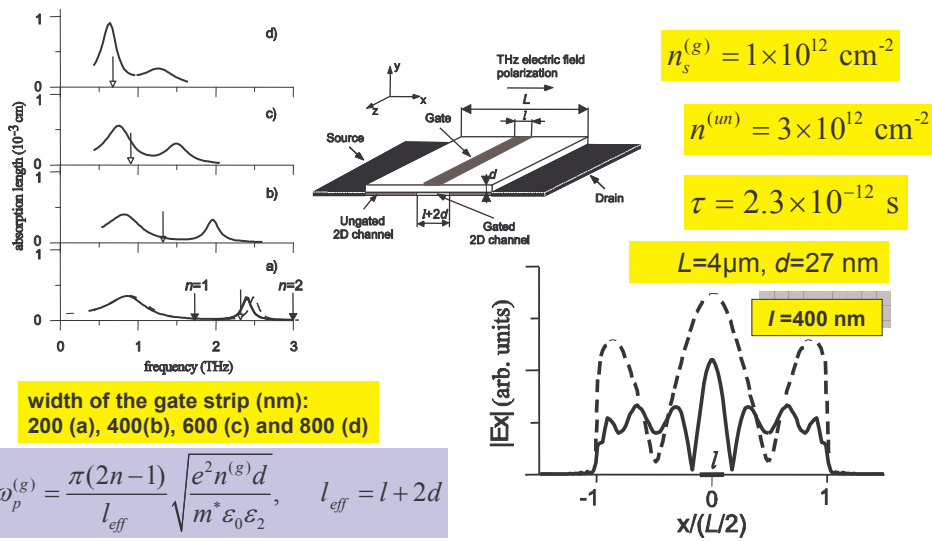
**InGaAs 60-nm-wide gate HEMT
(Courtesy of W. Knap)**

A Single-Gate InGaAs/InAlAs HEMT

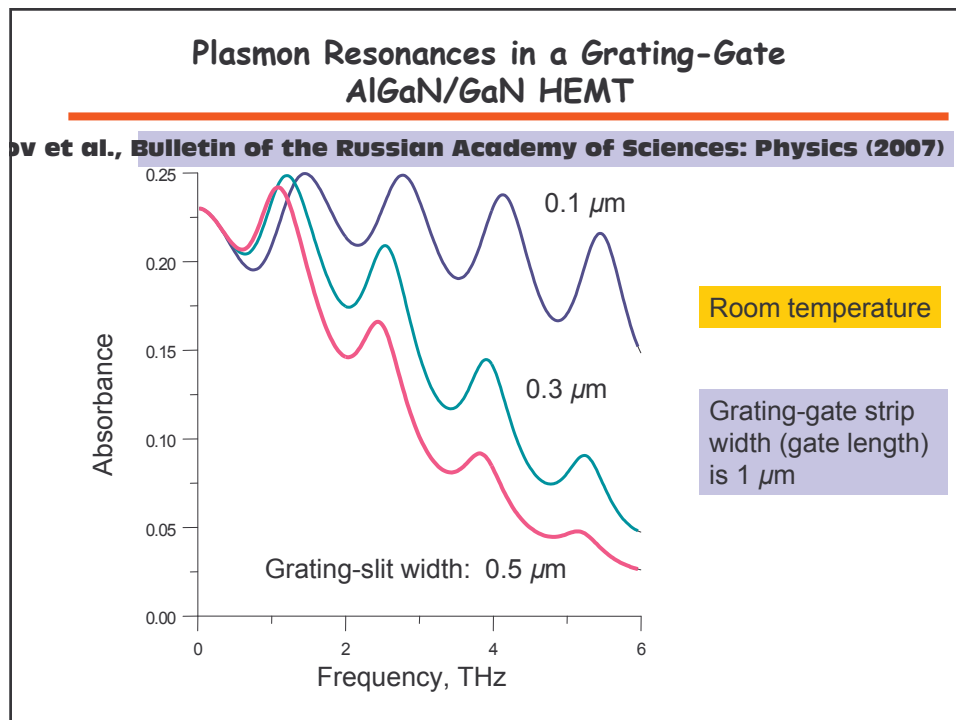
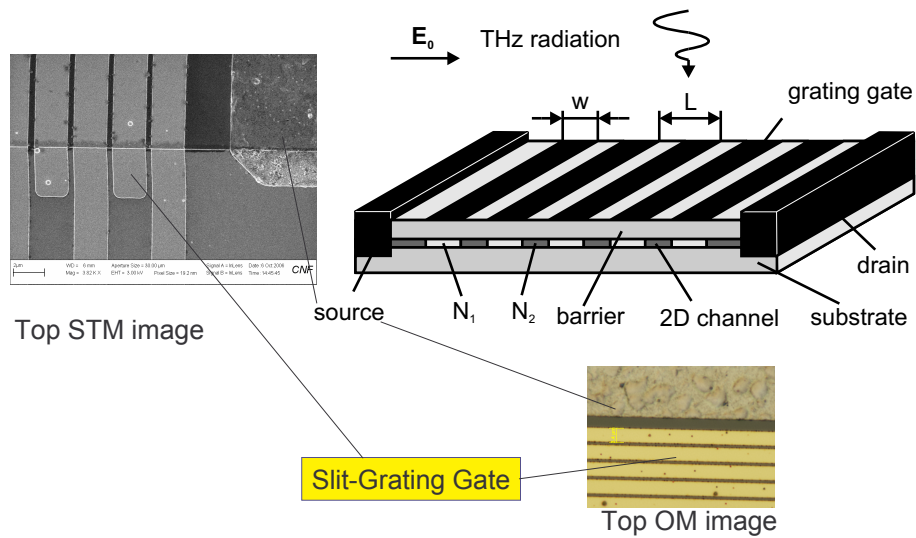


Parenty et al., Proc IPMR Conf., Nara 2001, p. 626 - 629

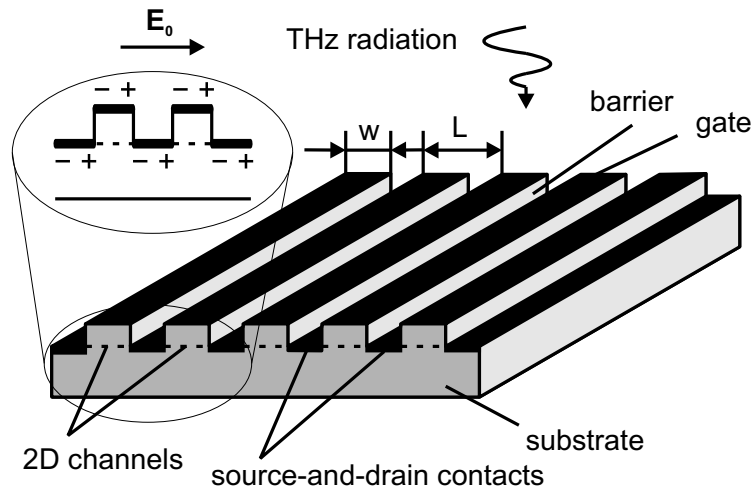
Tunable Screening of Inter-Contact Plasmons by a Recessed Gate



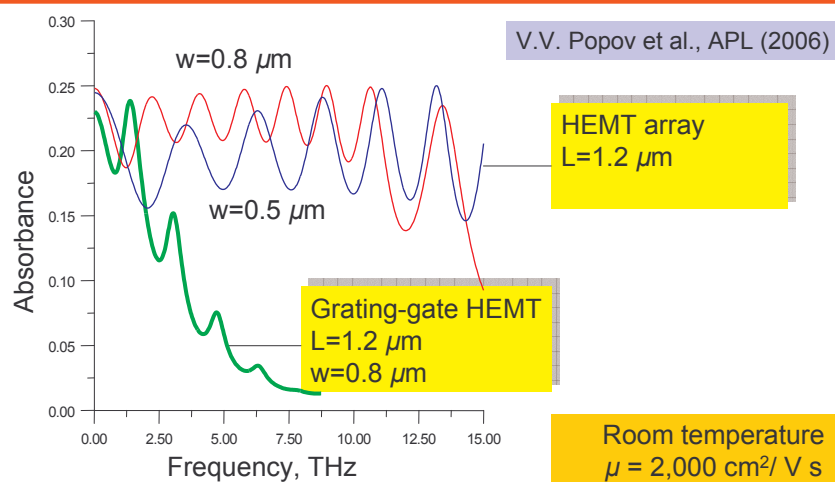
FET Structure with a Common Channel and a Large Area Grating-Gate



FET Array with Separate Channels



Plasmon Resonances in a AlGa_N/Ga_N HEMT periodic array



Plasmon absorption per unit area of the array in the model of non-interacting FET units is less than 10^{-3} !!!

Conclusions

- Electromagnetic approach is important to describe plasma oscillations in FET-like microdevices at THz frequencies
- Maximum resonant absorption takes place when the dissipative broadening of the plasma resonance is equal to its radiative broadening
- High-frequency resistance of a slot diode may be measured from contactless measurements of the characteristic electromagnetic lengths of the diode
- Gated plasmons under a sub-micron gate exhibit short scattering length and, therefore, they can not couple effectively to THz radiation
- Gated plasmons interact effectively with ungated plasmons in the access regions of the channel. This phenomenon may be used for coupling the gated plasmons to THz radiation
- Higher-order inter-contact plasmon resonances can be tuned in frequency by a recessed gate
- HEMT arrays is effective for exciting higher-order plasmon modes in the channel due to strong cooperative coupling of plasmons to THz radiation, which makes possible to design THz plasmonic devices with operating frequencies up to 15 THz or even higher

Plasmonic Devices with 2D Electron Channel for THz Applications

THz Detectors and Mixers

M. Dyakonov and M. Shur, IEEE T-ED (1996)
K. Guven et al., PRB (1997)
V. Ryzhii et al., JAP (2002)
W. Knap et al., APL, JAP (2002)
X.G. Peralta et al., APL (2002)
A. Satou et al., SST (2003)
V.V. Popov et al., JAP (2003)
V. Ryzhii et al., JAP (2003)
F. Teppe et al., APL (2005)
I.V. Kukushkin et al., APL (2005)
D. Veksler et al., PRB (2006)

THz Generators

A.V. Chaplik, SSC (1988)
M. Dyakonov, M. Shur, PRL (1993)
K. Hirakawa, APL (1995)
K. D. Maranowski, APL (1996)
V.V. Popov et al., Physica A (1997)
S.A. Mikhailov, PRB (1998); APL (1998)
P. Bakshi et al., APL (1999)
N. Sekine et al., APL (1999)
R. Bratshitsch et al., APL (2000)
Y. Deng et al., APL (2004)
W. Knap et al., APL (2004)
M. Dyakonov and M.S. Shur, APL (2005)
N. Dyakonova et al., APL (2006)

**Photonics Laboratory of the Institute of
Radioengineering and Electronics in Saratov**



Thank you for your attention!